

Dependence of Optical Response Time on Gate-to-Source Voltage for InAlAs/InAs/InGaAs Pseudomorphic High Electron Mobility Transistors

Takahisa Ando, Hirohisa Taguchi, Kazuya Uchimura, Miho Mochiduki,
Tsutomu Iida and Yoshifumi Takanashi

Department of Materials Science and Technology, Faculty of Industrial Science and Technology
Tokyo University of Science

2641 Yamazaki, Noda, Chiba Pref., 278-8510 Japan

Telephone +81 4 7124 1501 Ext. 4368, Facsimile +81 4 7122 1499 E-mail: ht0131@rs.noda.tus.ac.jp

1. Introduction

InP-based high electron mobility transistors (HEMTs) have shown great success in microwave and millimeter applications. Especially, HEMTs with a pseudomorphically strained InAs channel (InAs-PHEMTs) have superior electron transport properties and high electron density, which are due to a large conduction band discontinuity [1]. The current-gain cutoff frequency (f_t) of 628 GHz [2] and the maximum oscillation frequency (f_{max}) of 1.2 THz have been reported [1]. Recently, we have demonstrated that these InAs-PHEMTs can operate as not only a high speed transistor but an ultra-high speed optical receiver [3-5]. In addition, we have shown the dependence of the optical response on the drain-to-source voltages (V_{DS}) for InAs-PHEMTs and have made clear the physical mechanism for the response time [6].

In this work, we show the dependence of the optical response on the gate-to-source voltages (V_{GS}) for InAs-PHEMTs. They exhibited an ultra-high optical response with a response time as low as 20 ps. To physically understand those optical responses, we estimated the minority carrier lifetime τ using Auger recombination theory [5, 6].

2. Experiment

2.1. Device structure

We examined the pseudo-morphic channel of an InAs-PHEMT that was composed of the following layers: In_{0.53}Ga_{0.47}As (2 nm), InAs (3 nm), In_{0.7}Ga_{0.3}As (7 nm), and In_{0.53}Ga_{0.47}As (6 nm) [4]. Figure 1 shows an InAs-PHEMT structure we used. Since a lower growth temperature is required to grow the strained layers, we grew the pseudomorphic HEMTs at 673 K.

2.2. Experimental setup

Figure 2 shows the experimental setup we used for measuring the optical response. In this experiment, the optical pulse from a fiber laser with an emission wavelength of 1.55 μm and a pulse width of 400 fs was illuminated from the backside of the substrate [3, 4].

3. Results and discussion

Figure 3 plots typical drain-current voltage characteristics for InAs-PHEMTs at room temperature (RT).

Note that the figure indicates good pinch-off behavior, with the value of the threshold voltage (V_{th}) being about -0.35 V.

Figure 4 shows the optical response characteristics for InAs-PHEMTs at drain-to-source voltage, $V_{DS} = 1.4$ V for four values of V_{GS} . A digitizing oscilloscope measures the transient characteristics of induced photocurrent by the change in output voltage through its 50- Ω input resistance (V_{out}). We have already shown in the previous papers [4, 6] that the V_{out} decreased exponentially and had two gradients, i.e. the measurement data consist of two components whose lifetimes are different. Therefore V_{out} due to the optical response of the HEMTs can be expressed as;

$$V_{out} = A_1 \exp(-t/\tau_1) + A_2 \exp(-t/\tau_2)$$

Where τ_1 and τ_2 represent the lifetimes, A_1 and A_2 being constants.

Figure 5 shows τ_1 and τ_2 as functions of V_{GS} . As we have clarified from the V_{DS} dependence of measured lifetime [6], τ_1 is the time for a hole to transit the gate region (τ_t) and τ_2 the Auger recombination time (τ_A). In this figure, τ_1 and τ_2 decreased with decreasing V_{GS} and were saturated at V_{GS} less than -0.3 V. It is well-known from the device simulation that the electron velocity (v_e) increases with decreasing V_{GS} because of an increase in the channel field [7]. By the same reasoning, the hole velocity (v_h) also increases with decreasing V_{GS} . This is the reason why τ_t decreases with decreasing V_{GS} . According to our previous work in which the Schrödinger equations for electrons and holes were solved simultaneously [8, 9], the distributions for electrons and holes change depending on V_{GS} since the electrostatic potential profile under the gate region changes. At a higher V_{GS} , furthermore, electrons tend to distribute around the upper heterointerface and conversely holes around the lower heterointerface. At a lower V_{GS} , on the other hand, both electrons and holes coexist in the InAs channel. Therefore, the Auger recombination rate increases and hence the Auger recombination time decreases with decreasing V_{GS} . This is the reason why τ_A decreases with decreasing V_{GS} .

Next, we estimated the Auger lifetime (τ_A) using Fermi-Dirac statistics and the k-p band theory. The details of the theory and the calculation procedure are described elsewhere [4]. Figure 6 shows the calculated results of τ_A , the radiative lifetime (τ_R), and the total lifetime (τ_{Total}) as a function of the injected carrier concentration (Δn) at n_0 of $2 \times 10^{18} \text{cm}^{-3}$. Here n_0 corresponds to the average 2DEG concentration of the InAs channel [4]. Obviously, the Auger

mechanism dominates the recombination process in InAs. Using the value of τ_A (1.8×10^{-11} s) experimentally obtained, it was found that the concentration of holes, accumulated in the source region, reaches as large as $2.8 \times 10^{18} \text{ cm}^{-3}$.

4. Conclusions

InAs-PHEMTs exhibited an ultra-high optical response with a response time as low as 20 ps. The experimental results can be explained using two different lifetimes, one being dominated by the time for a hole to transit the channel under the channel field (τ_t) and the other dominated by the Auger recombination time (τ_A). The dependences of τ_t and τ_A on V_{GS} can be explained by the change of the channel field and by the change of the distributions of electrons and holes, respectively. The minimum values of τ_t and τ_A was as low as 8.1×10^{-12} s and as low as 1.8×10^{-11} s, respectively. From the calculation using the Auger recombination theory, it was found that the concentration of holes, accumulated in the source region, reaches as large as $2.8 \times 10^{18} \text{ cm}^{-3}$.

References

[1] R. Lai, X. B. Mei, W. R. Deal, W. Yoshida, Y. M. Kim, P. H.

Liu, J. Lee, J. Uyeda, V. Radisic, M. Lange, T. Gaier, L. Samoska and A. Fung, Proceedings of International Electron Devices Meeting 07 (IEDM2007), (2007) 609.

[2] D.-H. Kim and J. A. del Alamo, IEEE Electron Device Lett., **29** (2008) 830.

[3] H. Taguchi, C. Sano, H. Murakami, M. Oura, T. Iida, and Y. Takanashi, Phys. Stat. Sol. (c), **5** (2008) 2791.

[4] H. Taguchi, N. Wakimura, Y. Nakamura, T. Iida and Y. Takanashi, Phys. Stat. Sol. (c), **6** (2009) 1386.

[5] N. Wakimura, Y. Nakagawa, H. Taguchi, T. Iida, and Y. Takanashi, Mater. Res. Soc. Symp. Proc., **1108** (2009) 1108-A09-02.

[6] H. Taguchi, Y. Oishi, T. Ando, K. Uchimura, M. Mochiduki, M. Enomoto, T. Iida and Y. Takanashi, Jpn. J. Appl. Phys., **49** (2010) 04DF03-1.

[7] For example, R. Yamada, T. Takegishi, Y. Hirata, T. Matsumoto, S. Hara and H. I. Fujishiro, Phys. Stat. Sol. (c), **6** (2009) 1403.

[8] H. Taguchi, M. Kawaguchi, M. Hayakawa, Y. Nakamura, T. Iida and Y. Takanashi, Jpn. J. Appl. Phys., **45** (2006) 4960.

[9] H. Taguchi, H. Murakami, M. Oura, T. Iida and Y. Takanashi, Jpn. J. Appl. Phys., **45** (2006) 8549.

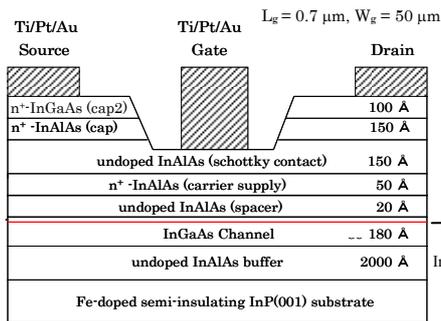


Figure 1 The InAs-PHEMT structure.

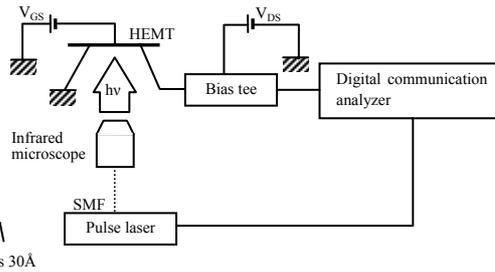


Figure 2 The experimental setup.

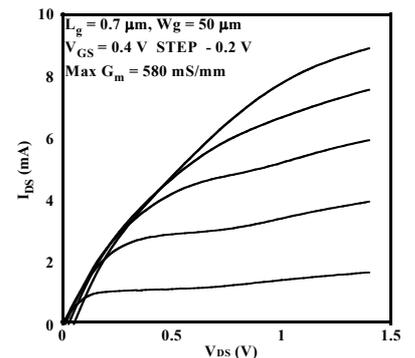


Figure 3 Typical drain-current voltage characteristics for InAs-PHEMTs at room temperature.

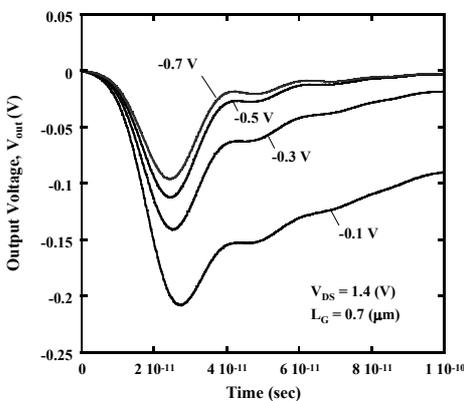


Figure 4 The optical response characteristics for InAs-PHEMTs at $V_{DS} = 1.4$ V for four values of V_{GS} .

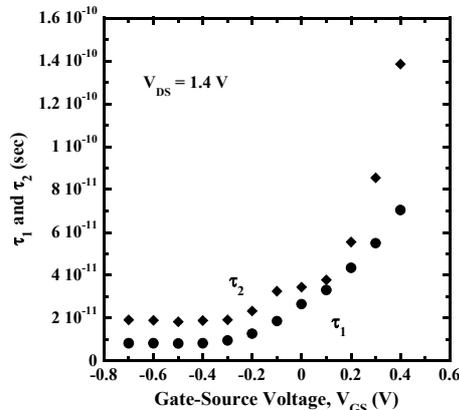


Figure 5 τ_1 and τ_2 as functions of V_{GS} .

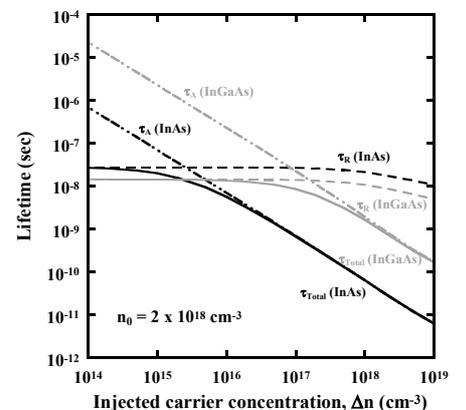


Figure 6 Theoretical results of the Auger lifetime τ_A , the radiative lifetime τ_R , and the total lifetime τ_{Total} as functions of the injected carrier concentration, Δn , at n_0 of $2 \times 10^{18} \text{ cm}^{-3}$.